Nidec Advance Technology Corporation

December 10, 2025

Nidec Advance Technology to Exhibit Products at SEMICON Japan 2025

Nidec Advance Technology Corporation (“Nidec Advance Technology” or “the Company”) announced today that it will exhibit products at SEMICON Japan 2025, an event scheduled to be held at Tokyo International Exhibition Center (Tokyo Big Sight) from Wednesday, December 17 – Friday, December 19, 2025.

In this upcoming exhibition, under the theme “One Stop Solution,” the Company will display state-of-the-art solutions for AI servers and power semiconductors. Also exhibited will be AI technology-based AVI and 2D/3D optical inspection devices optimum for panel level packages and base-board products, and electric property inspection equipment for wafers (KGD)/modules for IGBT/WBG devices, etc., among other products and solutions. Nidec Advance Technology will also propose probe cards to satisfy anti-heat measures and other emerging inspection-related needs, and other cutting-edge inspection technologies that meet market demands.

About SEMICON Japan 2025:
- Period: Wednesday, December 17 – Friday, December 19, 2025
- Venue: East Exhibition Tower, Tokyo Big Sight
- Booth: 4Hall E4922
- Official website: https://www.semiconjapan.org/en

Nidec Advance Technology’s exhibits will include:

- **RWi-300MK3 (optical inspection apparatus)**: Uses AI technology for 2D and 3D inspections.
- **NATS Series (inspection equipment for power semiconductors)**: Applicable to IGBT/WBG devices.
- **Probe card with a high-voltage-resistant pressurized structure**: Uses anti-discharge measures.
- **Device temperature measurement probe**: Uses thermocouple technology.
- **2D-MEMS probe card**: Uses the 2D-MEMS technology to accommodate CMOS image sensors.
- **Probe card for vertical narrow pitches**: Uses a high-precision plating technology to accommodate narrow pitches (55µm).
- **NS Probe**: Uses the MEMS process to realize miniaturization and special shapes.
- **EFEM (automatic transport machine)**: Capable of handling factory automation.
- **GATS-8360A (energization inspection equipment)**: For AI- LEO satellite substrates.
- **GATS-7885 (energization inspection equipment)**: For PLP/Interposers.

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